

# INFOVION's

## Ion Beam Sputtering System **IBS System**



**ISB-1000**  
Ion Beam Sputtering System

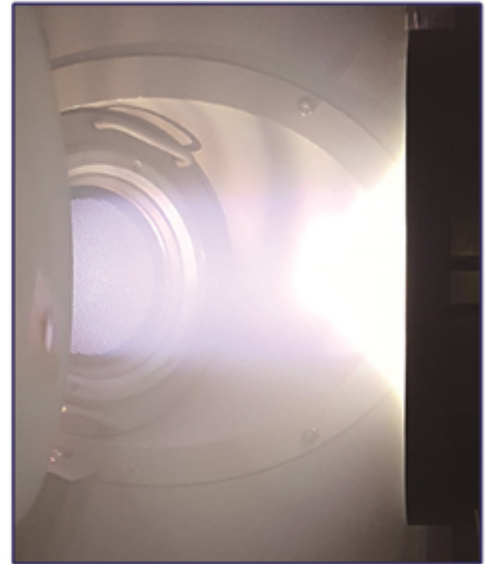
**INFOVION's IBS System Provides**  
the Best Available Value for Wide Range of Production Applications.

### *System Features*

- ➔ Ion Beam Sputtering System for a Functional Multilayer Coating
- ➔ High Quality Thin Film Deposition for Good Optical Property
- ➔ Optimized Ion Beam Source for Sputtering & Assistance
- ➔ High Speed Rotation for Thickness Uniformity
- ➔ Possible to Use Recipe for Running Process Automatically

# Ion Beam Sputtering System IBS System

ISB-1000



## → Specification

- Deposition Mode : Ion Beam Sputtering with Ion Beam Assistance
- Sputtering Ion Beam Source :  $\varnothing 140 \sim \varnothing 150$  RF Ion Source with Neutralizer
- Assist Ion Beam Source :  $\varnothing 140 \sim \varnothing 150$  RF Ion Source with Neutralizer
- Coating Material :  $\text{SiO}_2$ ,  $\text{Ta}_2\text{O}_5$ ,  $\text{TiO}_2$ ,  $\text{HfO}_2$ , NiCo etc, Optical Multi Layer thin film
- Substrate : 4ea Planetary High Speed Rotation Turntable
- Coating Area : 4ea  $\varnothing 300\text{mm}$  Planetary Substrate
- Substrate Heating Temperature :  $\sim 300^\circ\text{C}$
- Gas Control : Ar,  $\text{O}_2$ ,  $\text{N}_2$
- Ultimate Pressure :  $\leq 5.0 \times 10^{-7}$  Torr
- Operating System : Fully Automated Recipe Control by PC System

## - HMI Program -

